

20 DEC 2001 IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	
,	Atty. Docket No.: TSUK 0005
CHIBA, Tatsuo, et al.	
Serial No (corresponding to PCT/JP00/04028 filed 21 June 2000)	5/A D.G.
Filed: Herewith	3-12-02
For: PHOTOSENSITIVE ELEMENT,	
PHOTOSENSITIVE ELEMENT ROLL,	
PROCESS FOR THE PREPARATION	
OF RESIST PATTERN USING THE	
SAME, RESIST PATTERN, RESIST	
PATTERN LAMINATED)
SUBSTRATE, PROCESS FOR THE	
PREPARATION OF WIRING	Date: 20 December 2001
PATTERN AND WIRING PATTERN)

PRELIMINARY AMENDMENT (A)

BOX: PCT (DO/EO/US)

Assistant Commissioner for Patents

Washington, D. C. 20231

Sir:

Prior to calculating the filing fee, kindly amend the above-captioned application as follows:

IN THE CLAIMS:

Kindly amend claims 20, 22, 29-31 and 40 and replace them with the following:

20. (Amended) A photosensitive element roll according to Claim 1, wherein the above photosensitive element is wound up or rolled around a core.

22. (Amended) A process for preparing a resist pattern which comprises laminating the photosensitive element according to Claim 1 to a substrate for forming a circuit so that the photosensitive resin composition layer is closely contacted to the substrate, irradiating imagewisely active light to photocure the exposed portion, and removing an unexposed